

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: S. KADLEC, et al.

Serial No: 10/798,331

Filed: March 12, 2004

Title: METHOD FOR MANUFACTURING SPUTTER-COATED  
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING  
CHAMBER WITH SUCH SOURCE

Group: 1795

Examiner: Michael A. Band

Conf. No.: 6134

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 30, 2009

Sir:

In response to the personal interview on November 13, 2009, please amend the above-identified application as listed below and as set forth on the following pages:

Amendments to the Specification

Amendments to the Claims

Amendments to the Drawings

Remarks are included following the amendments.